

Copper Diffusion at the Copper/Silicon Interfaces: Is it really that big a problem?

Yuelin Xiong¹ and Sebastian Bonilla¹

¹Department of Materials, University of Oxford, UK

DEPARTMENT OF MATERIALS

Electronic and Interface

Materials Laboratory

http://interface.materials.ox.ax.uk

Introduction

Copper metallisation as silver alternative:



- ~80 times cheaper, ~800 times more abundant than Ag
- high conductivity → lower finger resistance
- thin finger width → less shading loss

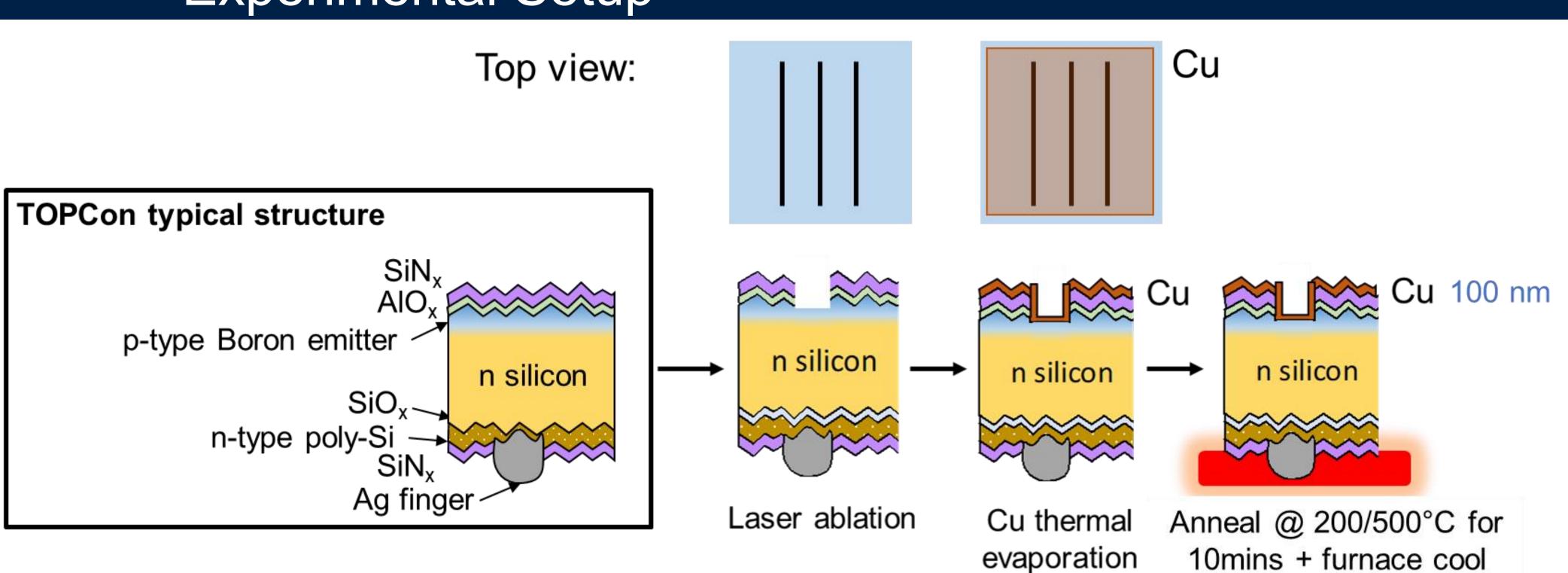


 Cu has high diffusivity in Si → Highly active deep-level recombination centre → Degrades cell performance [1].

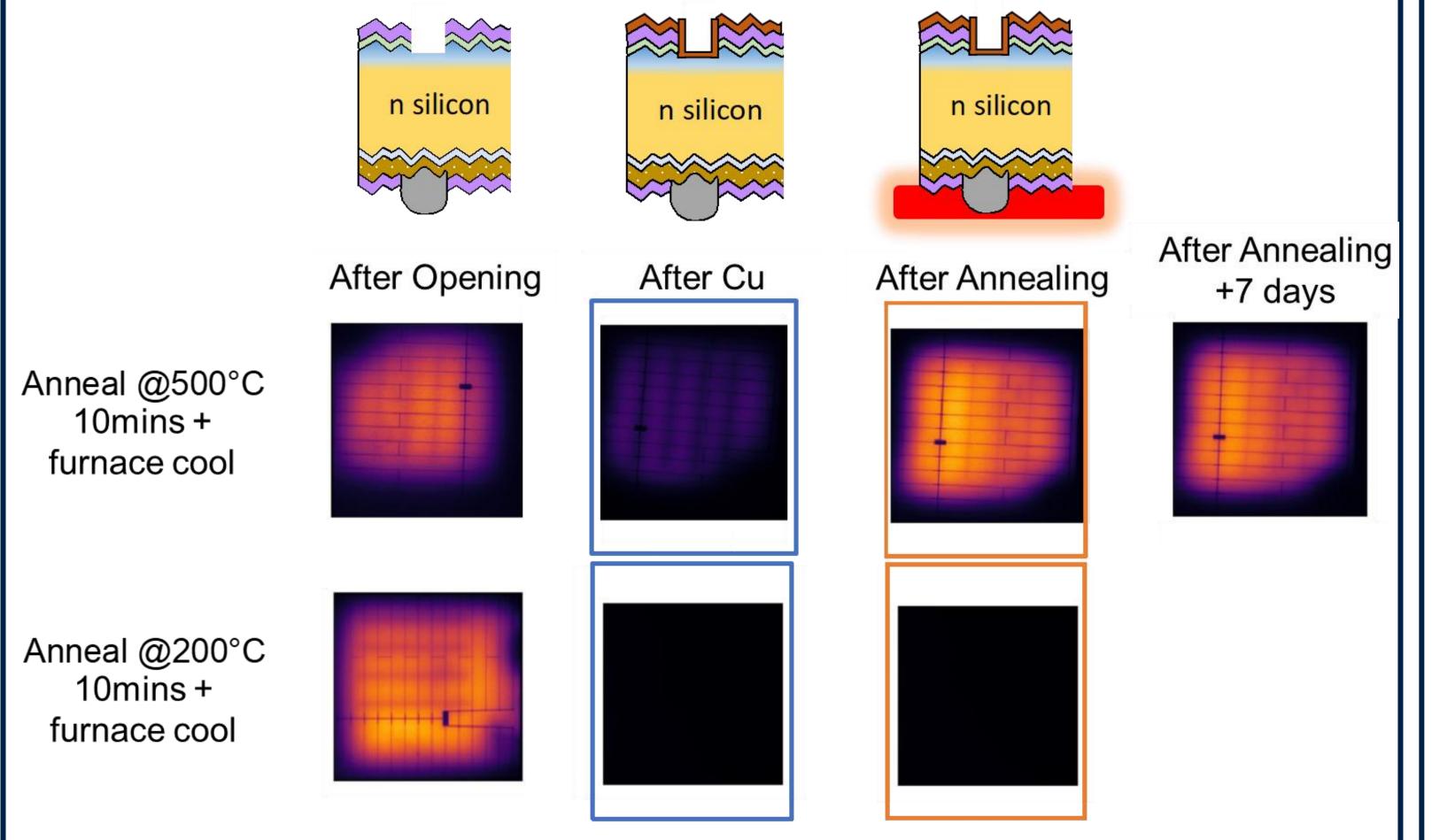
But is it really that big a problem?

Experimental Setup

- UV picosecond laser openings on the AIO_x/SiN_x stack.
- Thermal evaporation of Cu on the front side.
- Heat treatment at 200 / 500 °C
- Detection of Cu diffusion via degradation in PL intensity.

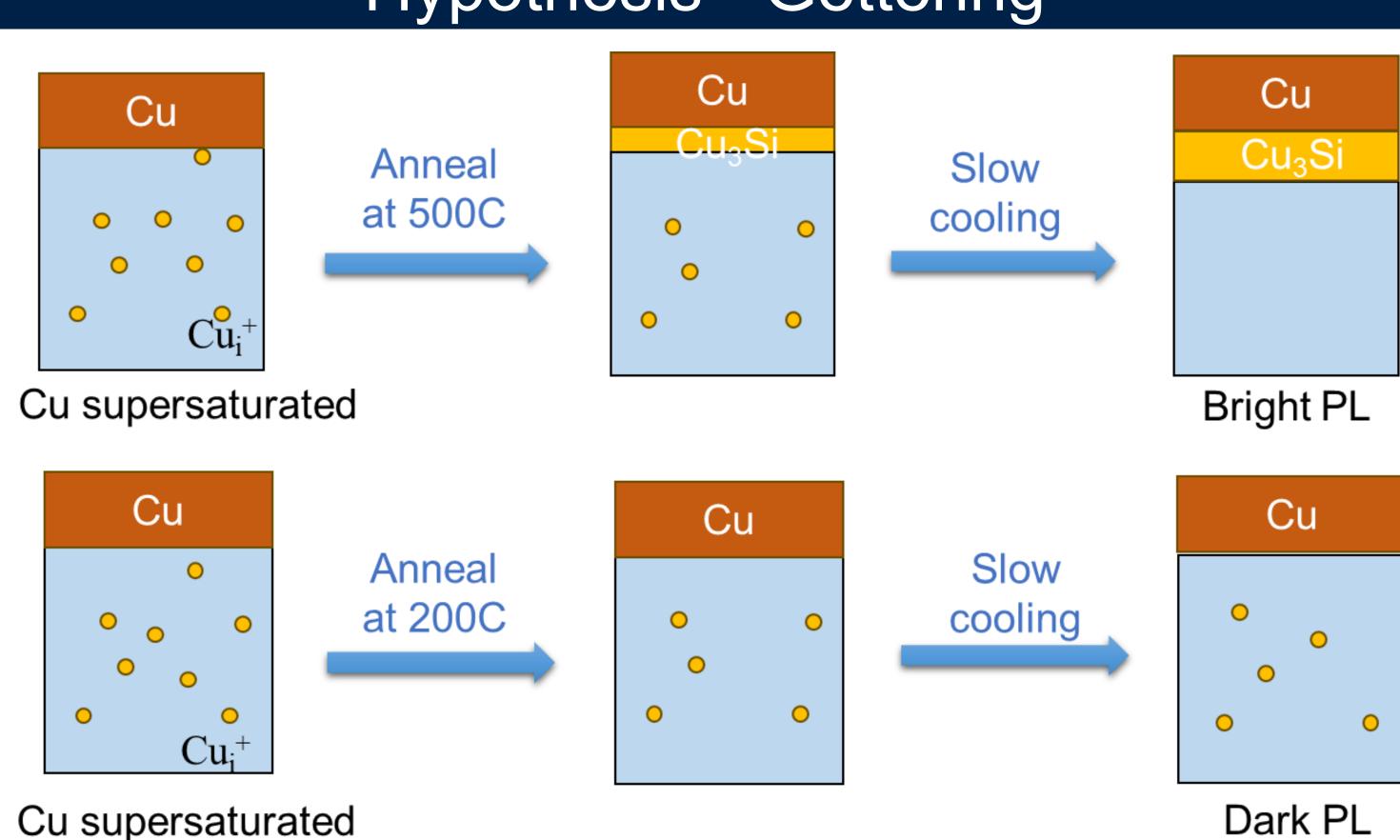


Annealing Cu/Si Contact at Different Temperatures



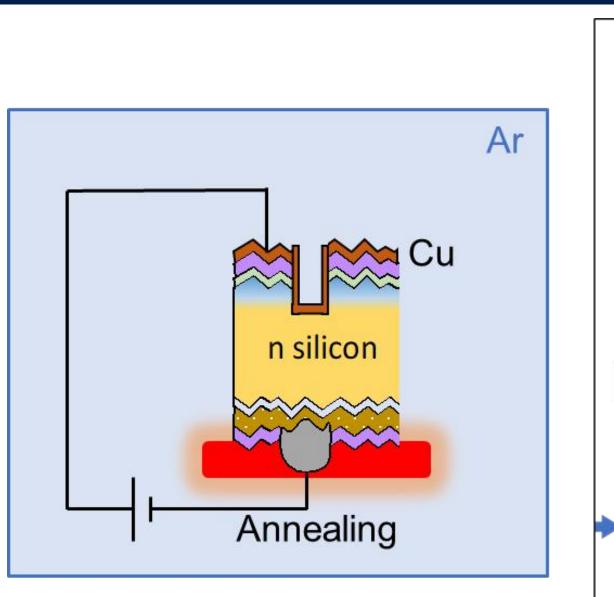
- Post-Cu Deposition: PL drops in Cu/Si contact regions due to defect-induced recombination.
- 500 °C Anneal → PL recovers, stable for 7 days → Defect recovery.
- 200 °C Anneal → PL remains dark → Defect remains in Si bulk.

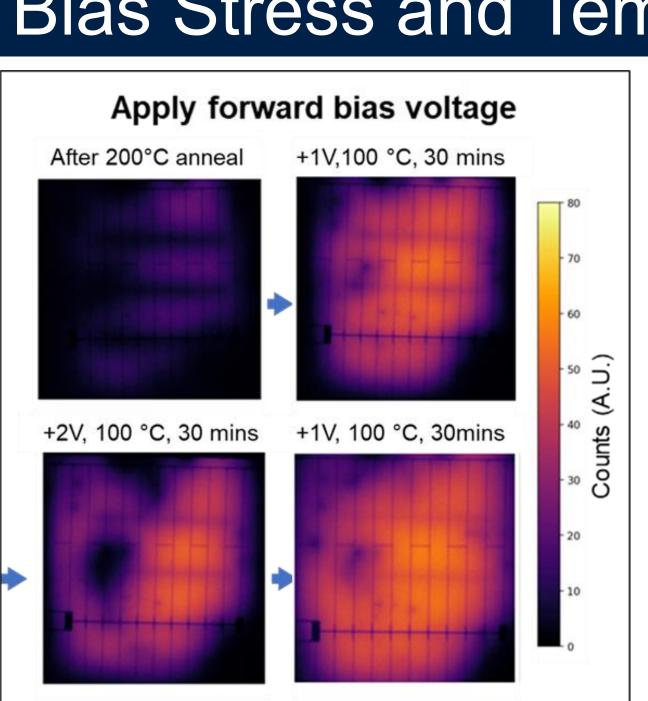
Hypothesis - Gettering



- **Gettering:** Removes impurities by trapping them in specific regions/layers to improve material properties.
- 500 °C Anneal → Cu-silicide/Cu colonies form
 → Cu diffuses towards gettering sites → Fewer bulk defects.
- 200 °C Anneal → No Cu-silicide/Cu colonies
 → Cu remains in Si bulk → No gettering.

Forward Bias Stress and Temperature





- Bias & temperature recover Cu-induced defects.
- Could be driven by chemical potential gradient.

Conclusions

- Cu-induced degradation is reversible after a 500 °C anneal, restoring effective carrier lifetime.
- 200 °C anneal shows no recovery.
- Copper remains a promising alternative for solar cell metallisation.

[1] A. A. Istratov, et al, 'Intrinsic Diffusion Coefficient of Interstitial Copper in Silicon', Phys. Rev. Lett..





